



MEMS Retard & Impact Sensors

Principal: Walter Maurer, NAWCWD China Lake

Contributors:

Dr. Daniel Jean, NSWC Indian Head

Ryan Knight, ARDEC



Objective

➤ ***Exploit existing MEMS microfabrication and packaging technologies to realize DoD retard and impact sensors with improved performance:***

- ***precision***
- ***reliability***
- ***producibility***
- ***cost effectiveness***



➤ **Improved G-sensor performance for existing & future fuzes including:**

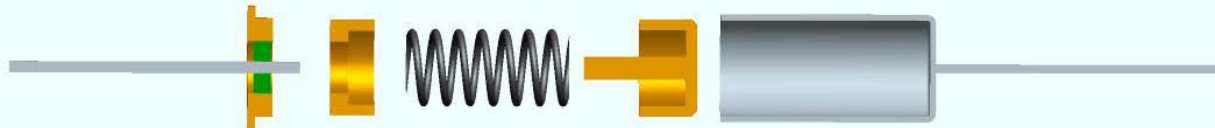
- ***FMU-139 (impact sensor; retard sensor)***
- ***FMU-143 (impact sensor)***
- ***High Reliability Fuze (impact sensor)***
- ***Hardened freefall weapon fuzing applications***





➤ **Traditional coil-spring-mass technology:**

- **Wider variability in performance than MEMS**
 - *wire & coil dimensional tolerances*
 - *coil winding stresses & annealing*
- **Difficult to precisely sense low G's with "macro world" springs**

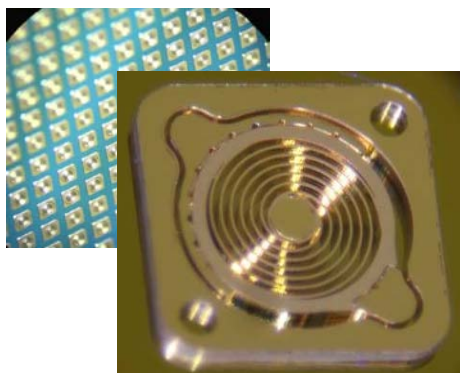


Background (cont.)

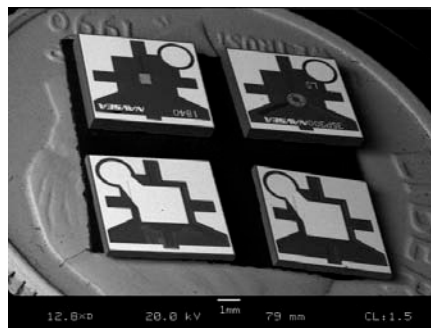


➤ **Newer MEMS-technology appears well-suited for making improved low-G sensors per DoD exploratory work to date:**

- **ARDEC: metal G-sensors and packaging**
- **NSWCIH: silicon G-sensors and packaging**
- **NAWCWD: precision-electroplated G-sensors**



Courtesy of ARDEC



Courtesy of NSWCIH

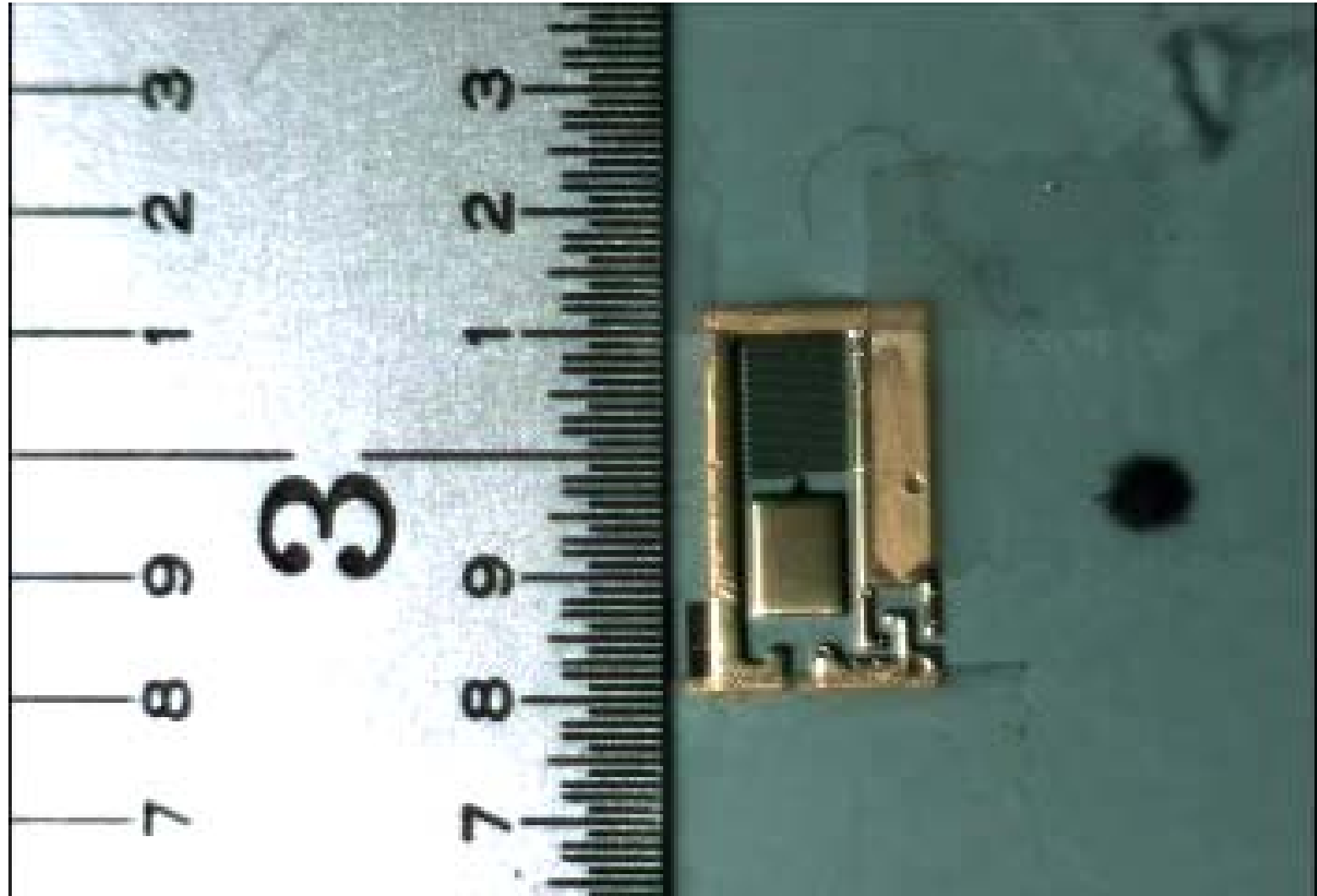


NAWCWD 5G Sensor (2005)

Background (cont.)



Centrifuge Test of Low-G Sensor in 1G Increments



Technical Approach



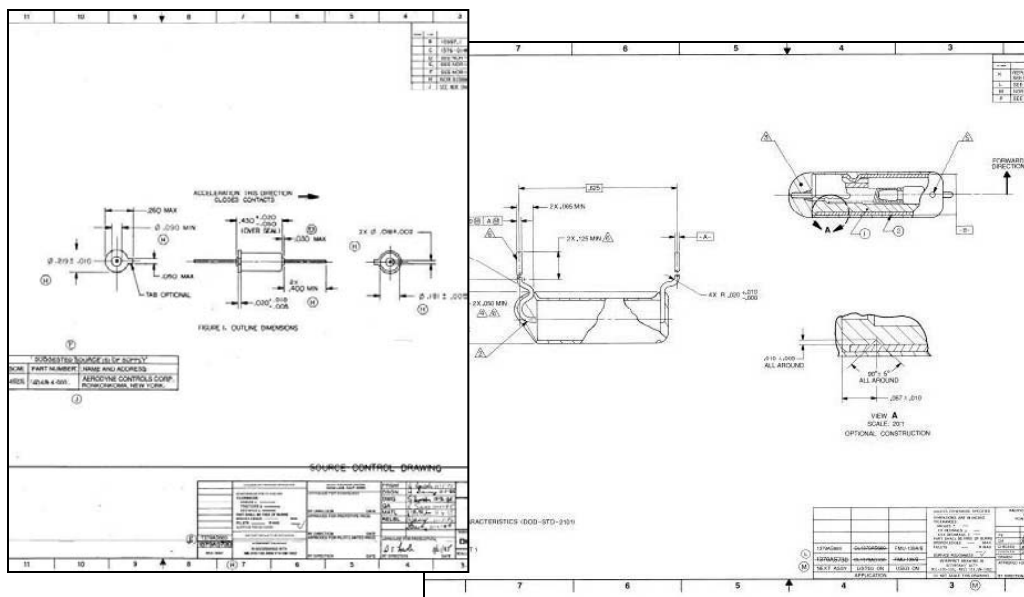
- **Modify existing NSWC and ARDEC sensor designs to duplicate performance of currently-fielded non-MEMS sensors**
 - **low-G impact sensors (<100G)**
 - **very low-G retard sensors (<5G)**
- **Fabrication**
 - **ARL (NSWC sensors); HT-Micro (ARDEC sensors)**
- **In-House Packaging & Testing**

1st-Year Progress



➤ Requirements obtained for bomb fuze sensors

- Retard sensor: 1.9G no-go, 2.3 all-go
- Impact sensor: 40G no-go, 80G all-go. Velocity change of 2 fps will cause closure.

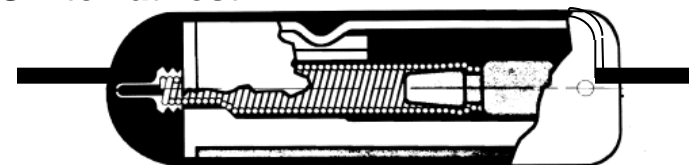


Production Drawings of Retard Sensor (left) & Impact Switch

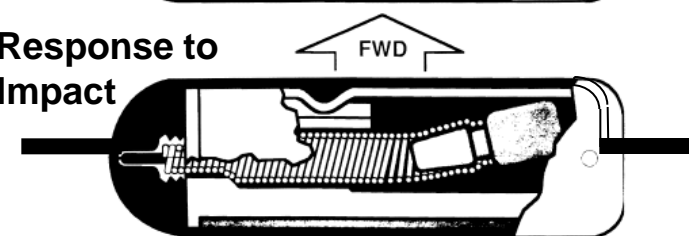


Impact Switch

Switch at rest



Response to Impact



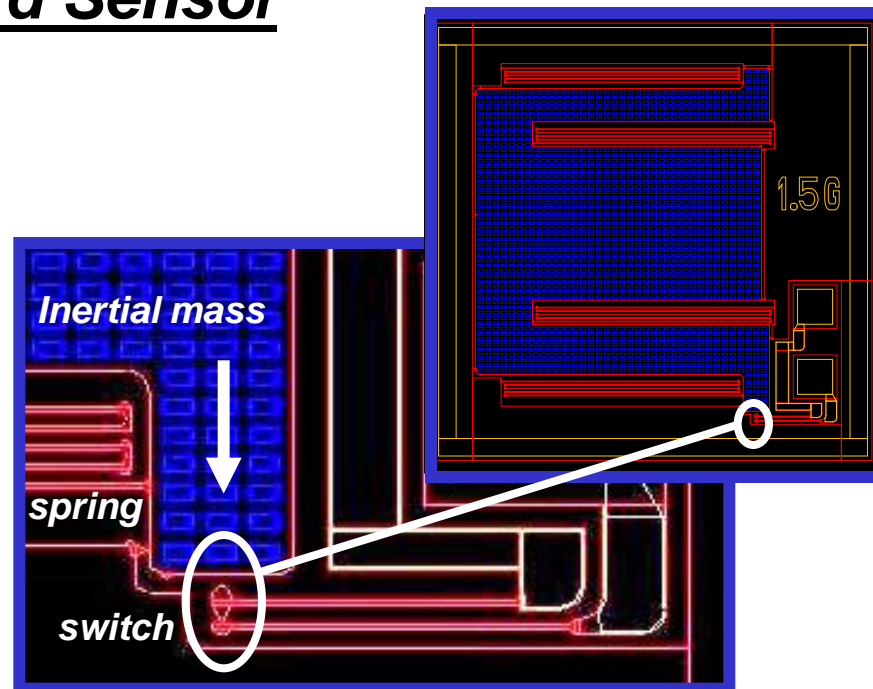
1st-Year Progress (cont.)



NSWCIH Retard Sensor

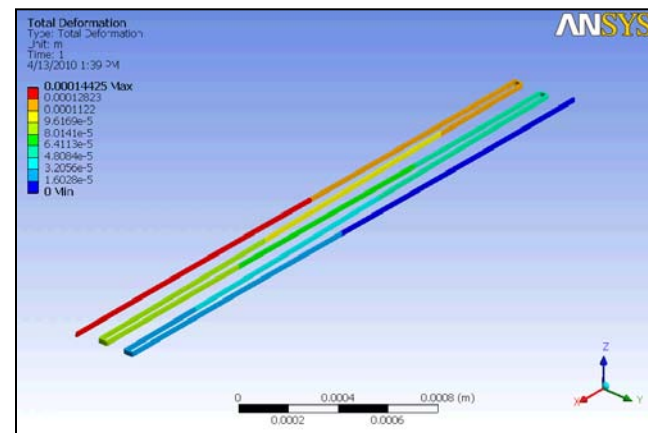
➤ *Design layout completed*

- Deep Reactive Ion Etching (DRIE)
- Design variations: 1.5, 2.1, 3.0, 4.0, and 5.0 G
- Unidirectional
- In-plane contact switch
- Chip size 5 x 5 mm



➤ *Simulation completed*

- Spring deflection under a static load ($k = 0.139 \text{ N/m}$)



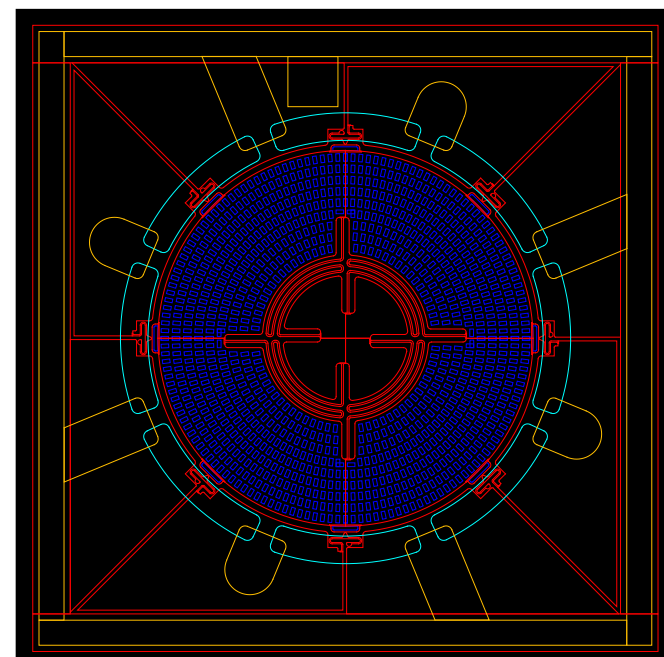


1st-Year Progress (cont.)

NSWCIH Impact Sensor

➤ **Design layout completed**

- Deep Reactive Ion Etching (DRIE)
- Various closure levels to bracket target performance
- Hemispherical contacts
 - 8 in-plane, 1 out-of-plane
- Chip size 5 x 5 mm



➤ **Simulation nearly completed**

- MATLAB-based dynamic modeling

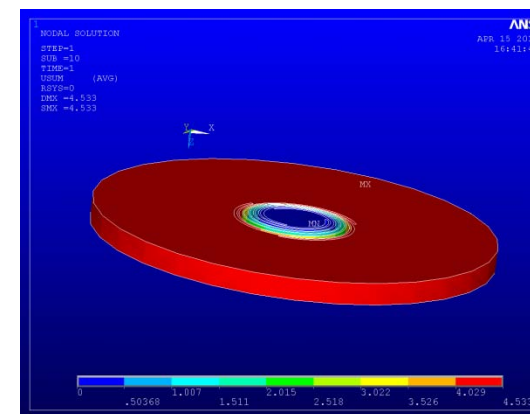
1st-Year Progress (cont.)



ARDEC Retard Sensor

➤ Preliminary modeling completed

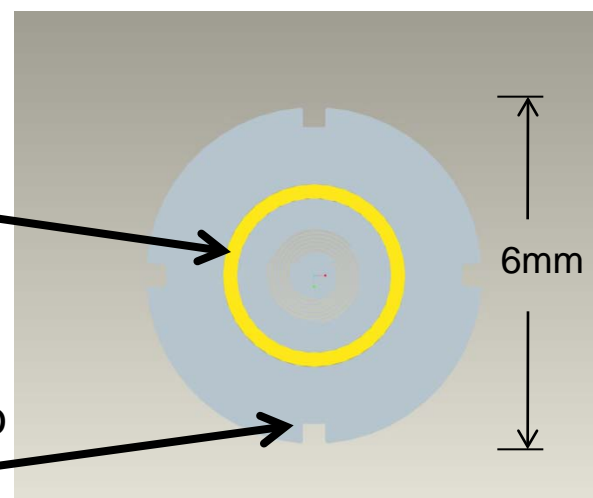
- Metal MEMS design to be made by htmicro
- 2.1 G
- Size ~ 6 x 6 x 1 mm



Preliminary FEA

Interior gold contact which only detects z-direction movements (will not detect rocking motion)

Anti-rotational features. Locks to keep proofmass from rotating




Preliminary ProE layout of MEMS 2.1G Retard Sensor

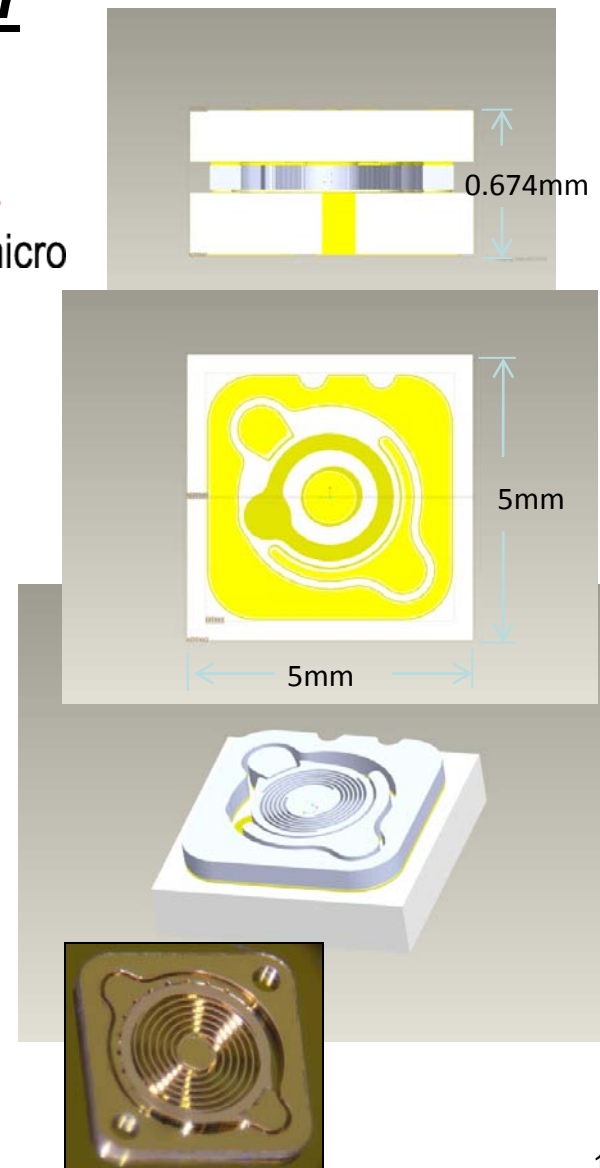
1st-Year Progress (cont.)



ARDEC Impact Sensor

➤ *Preliminary modeling completed*

- Metal MEMS design to be made by  htmicro
- Size ~ 5 x 5 x 0.67 mm
- Scaled version of successfully demonstrated 500G Impact Sensor
 - Over 100 data points collected with Mk19 40mm MEMS Integration fuze
 - Only two known failures
 - More data points to be collected in May 2010



1st-Year Progress (cont.)



ARDEC Impact Sensor (cont.)

➤ **Design Issues:**

- Tends to make contact in a rocking/rolling mode (similar to contact that a spinning penny makes as its spinning dies down). Thus, squeeze-film air damping is not utilized very well.
- This rocking motion will make contact under considerably lower inertial forces due to the moment created, thus affecting closure threshold.

1st-Year Progress (cont.)



Other ARDEC Design Issues

➤ ***Sensitivity to short duration impulses***

- increasing surface area will increase squeeze film and Couette damping, thus increasing sensor's g-seconds
- Higher nitrogen pressure during packaging

➤ ***Contact sticking***

- increase sputtered-gold contact's rhodium concentration

➤ ***Gap dimensions***

- ensure that spring remains in linear bending regime
- must be large enough to prevent lockup

1st-Year Summary



- ***G-sensor basic requirements have been identified***
- ***1st-iteration sensors have been designed & modeled***
- ***Layouts are nearly ready for fabrication***
- ***Fab contracts/delivery orders are in place***
- ***Additional info to be obtained for existing sensors:***
 - ***Resonance & response to orientation***
 - ***Production/Acceptance test requirements, methods & data***